Amendments to the Specification:

I. Please make changes to the following paragraphs as follows:

[0025] Fig. 2 is a diagrammatic illustration of multiple (e.g., four) microelectrical mechanical system (MEMS) optical raster display systems 10A-10D that have reflective surfaces 12A-12D on MEMS devices 14A-14D, respectively. Illumination light 16A-16D from light sources 18A-18D is directed toward reflective surfaces 12A-12D, respectively. MEMS devices 14A-14D pivot or oscillate reflective surfaces ~~10A-10D~~ 12A-12D in respective transverse directions 20A-20D and 22A-22D to reflect illumination light ~~16A-14D~~ 16A-16D toward display screen regions 24A-24D, respectively. The pivoting or oscillation in transverse directions 20 and 22 cooperate to direct light source 18 across display screen 26 in multiple raster scan patterns 28A-28D.

[0026] Modulation of light sources 18A-18D in coordination with the raster scanning of illumination lights ~~14A-14D~~ 16A-16D allows four 50x50 pixel raster scan patterns ~~26A-26D~~ 28A-28D to be imparted on display screen ~~24~~ 26. The raster-scanned image components are abutted or contiguous to provide a larger display (e.g., 200x200 pixels) than could be provided by a comparable MEMS raster display system 10 alone, as shown in Fig. 1.

[0027] Fig. 3 is a diagrammatic illustration of a Raster Arrays of MEMS Optical Display Systems (RAMODS) implementation in which a microelectrical mechanical system (MEMS) raster display system 50 has a reflective surface 52 on a MEMS device 54. Multiple illumination lights 56A-56D from light sources 58A-58D are directed toward reflective surfaces 52. MEMS device 54 pivots, tilts, or oscillates reflective surfaces 52 in two transverse directions 60 and 62 to reflect illumination lights ~~56A-54D~~ 56A-56D toward display screen regions 64A-64D, respectively. The pivoting or oscillation in transverse directions 60 and 62 cooperate to direct illumination lights 56A-56D across display screen 66 in raster scan patterns 68A-68D.

[0028] Modulation of light sources 58A-58D in coordination with the raster scanning of illumination lights ~~54A-54D~~ 56A-56D allows four 50x50 pixel raster scan patterns 68A-68D to be rendered on display screen ~~68~~ 66. The raster-scanned image components are abutted to or contiguous with each other to provide a larger display (e.g., 100x100 pixels) than could be provided by a comparable MEMS raster display system 10 employing only one light beam 16 (Fig. 1).

[0031] Modulation of light sources 58A1-58A4 and 58B1-58B4 in coordination with the raster scanning of illumination lights 56A1-56A4 and 56B1-56B4 allows eight 50x50 pixel raster scan patterns 68A1-68A4 and 68B1-68B4to be rendered on display screen 66. The raster-scanned image components are displayed contiguously to provide a larger display (e.g., ~~100x200~~ 100 x 100 pixels) than could be provided by a comparable MEMS raster display system 50 alone (Fig. 3).

[0032] It will be appreciated that arbitrary numbers of MEMS raster display systems 10 and 50 can be used together to form display images from arbitrary numbers raster scan patterns ~~28~~ 26 and 68. Likewise, the number of ~~illumination lights 56~~ light sources 58 that can be directed to a reflective surface 52 of MEMS raster display system 50 is also arbitrary within practical limits.